

ICPT 2026

October 19-22, 2026

Science and Technology Convention Center,
Seoul, South Korea

October 20 (Tue.), 2026

[Oral 05] AI & ML for CMP / Process Control

16:55-17:55

International Conference Hall (B1F)

● Session Chair: Chao-Cheng Arthur Chen (NTUST, Taiwan)

16:55-17:15 [AI-Enabled CMP Process Optimization in Advanced Semiconductor](#)
[Oral 05-1] [Manufacturing](#)

Cheng Zhongyao (Inst. for Infocomm Research (I2R), Singapore), [Su Myat Noe](#), Leong Lup San, Chen Gim Guan (Inst. for Microelectronics (IME), Singapore), Qian Peisheng, Ata Kircali Sezin, Gopinathan Arjunan, Ashish James (Inst. for Infocomm Research (I2R), Singapore), and Jun Hyunsu (Inst. for Microelectronics (IME), Singapore)

17:15-17:35 [Digital-Twin-Based Evaluation of Virtual Metrology for APC Performance in](#)
[Oral 05-2] [CMP](#)

[Seungchoun Choi](#), Yonghwan Yim, and Semyeong Oh (Amously Inc., Korea)

17:35-17:55 [Accelerating CMP Model Development Using Machine Learning for Early](#)
[Oral 05-3] [Manufacturability Risk Detection](#)

Ushasree Katakamsetty (Globalfoundries Singapore Pte. Ltd., Singapore), Henning Turnow, Boris Vasilev (Globalfoundries Dresden, Germany), Stefan Nikolaev Voykov (Globalfoundries, Bulgaria), [Ruben Ghulghazaryan](#), Davit Piliposyan (Siemens Industry Software, Armenia), and Jeff Wilson (Siemens EDA, USA)